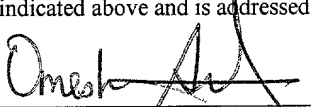


S/N unknown

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hubert Jerominek Serial No.: unknown  
Filed: concurrent herewith Docket No.: 9680.173USU1  
Title: METHOD OF FABRICATING A SUSPENDED MICRO-STRUCTURE  
WITH A SLOPED SUPPORT, AND A SUSPENDED MICROSTRUCTURE  
FABRICATED BY THE METHOD

<p>CERTIFICATE UNDER 37 CFR 1.10 'Express Mail' mailing label number: EL815525032US Date of Deposit: June 25, 2001 I hereby certify that this correspondence is being deposited with the United States Postal Service 'Express Mail Post Office To Addressee' service under 37 CFR 1.10 on the date indicated above and is addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.</p> <p>By:  Name: Omesh Singh</p>
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PRELIMINARY AMENDMENT

Assistant Commissioner for Patents  
Washington, D. C. 20231

Dear Sir:

In connection with the above-identified application filed herewith, please enter the following preliminary amendment:

IN THE CLAIMS

Please amend claim 19 as follows:

19. (amended) A suspended microstructure with a sloped support produced by the method of claim 1.

REMARKS

The above preliminary amendment is made to remove multiple dependencies from claim 19. A marked-up version of the claims is attached.

Applicants respectfully request that the preliminary amendment described herein be entered into the record prior to calculation of the filing fee and prior to examination and consideration of the above-identified application.

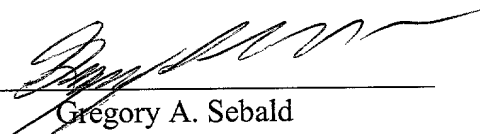
If a telephone conference would be helpful in resolving any issues concerning this communication, please contact Applicants' primary attorney-of record, Gregory A. Sebald (Reg. No. 33,280), at (612) 336.4728.

Respectfully submitted,

MERCHANT & GOULD P.C.  
P.O. Box 2903  
Minneapolis, Minnesota 55402-0903  
(612) 332-5300

Dated: June 25, 2001

By

  
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Gregory A. Sebald  
Reg. No. 33,280

GAS/jlc

12. A method according to claim 1, wherein the second temporary layer of step (a) is made of a polymer or made of glass.

13. A method according to claim 12, wherein the polymer is polyimide.

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14. A method according to claim 4, wherein the fifth planarization layer of step (i) is made of a polymer or made of glass.

15. A method according to claim 14, wherein the polymer is polyimide.

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16. A method according to claim 4, wherein the sixth layer of step (ii) is made of a material selected from the group including  $\text{SiO}_2$ ,  $\text{Si}_3\text{N}_4$ , Ti, Al, V, Au and Si.

15 17. A method according to claim 4, wherein the depositing of step (ii) is performed by means of a technique selected from the group including sputtering technique, resistive evaporation technique and electroplating technique.

20 18. A method according to claim 4, wherein the etching of step (iii) is performed by means of a reactive ion etching technique or a wet etching technique.

25 19. A suspended microstructure with a sloped support produced by the method of [anyone of the claims 1 to 18] --claim 1--